Characterization of VUV sensitive silicon photomultipliers (SiPMs)



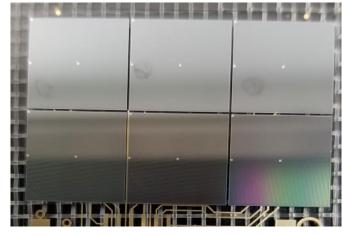
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Motivation

- Silicon photomultipliers (SiPMs) are emerging technology in photon detection in particle physics.
- Large future experiments like **nEXO**, **ARGO** etc. will use SiPM based light detection system



SiPM tile

Challenges

- Quality control and testing of these large number of SiPMs will be a challenge.
- A quick and reliable SiPM testing technique is required at all stages (from single SiPM to fully installed system).

Goals of this project

Current-voltage (IV) characterization of SiPM

Develop the IV fit model to understand the IV curves

Use fit model to extract the empirical parameters of SiPMs

Compare and verify the results from IV analysis with pulse analysis

Extend the study to different SiPM devices at a range of temperatures in different light conditions

VERA* setup at TRIUMF

SiPM devices

- FBK** VUV HD3
- Hamamatsu VUV4

Temperature range

• -110° C to +20° C

Light conditions

- Dark
- Light source 175nm & 385nm

Thanks to Dr. Fabrice Retiere and Dr. Mahsa Mahtab (TRIUMF) for their support in this project

mirror 2. Monochromator 1. Light source 5. Filter wheel (HHe) Referenc 6. Splitter mirror PMI 7. Shutter 8. Iris 9. Collimator 10. Sample wheel 11. I/V measurement/supply SiPM_ PMT (on rotating arm) 10 Translational (X) 13 12. Cold plate (sample stage) and LN lines 13. Liquid Nitrogen cooler 14. Turbo vacuum pump 15. Pressure gauge

6. Parabolic

VERA setup at TRIUMF used to take measurements for SiPMs

3. Manual slits

^{*}VERA - Vacuum Emission, Reflectance and Absorbance

^{**} FBK - Fondazione Bruno Kessler

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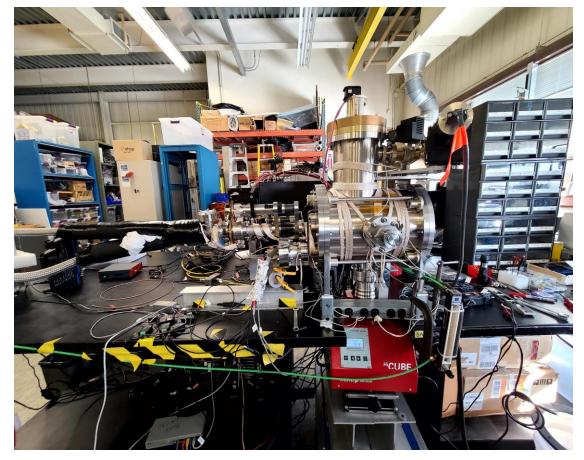
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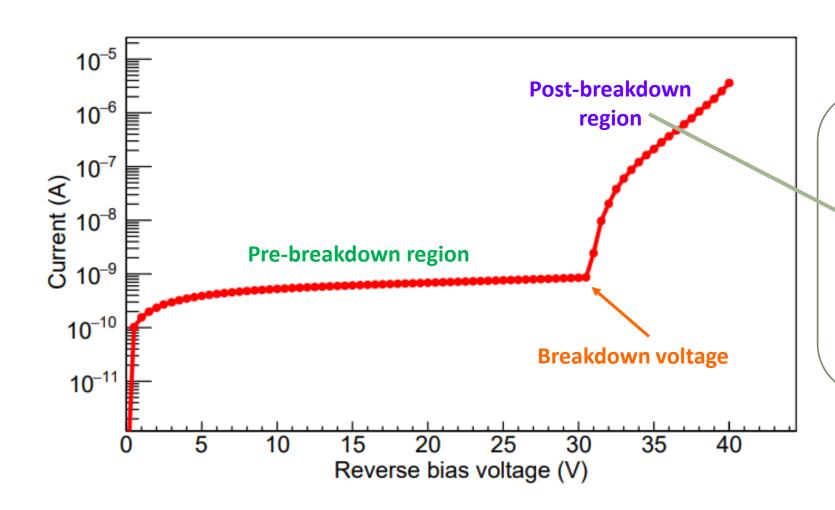


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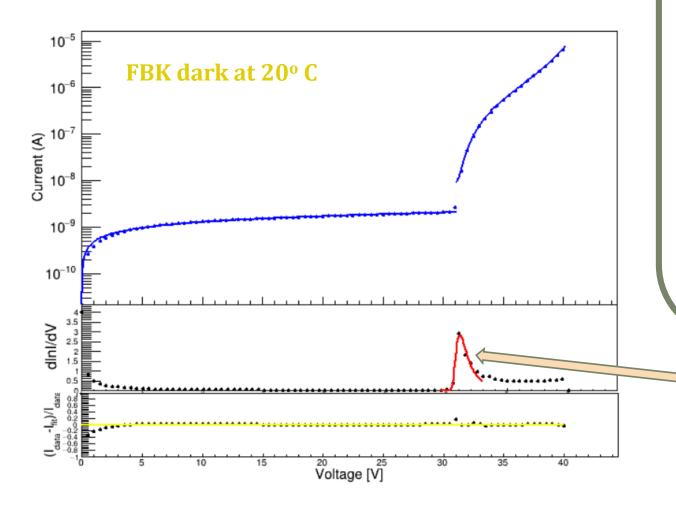
SiPM IV curve

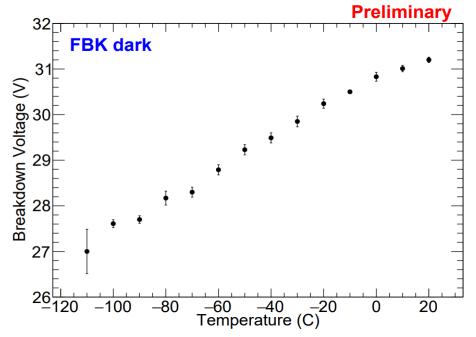


Post-breakdown region

- SiPMs are usually operated in post breakdown region
- Geiger mode a single charge carrier is able to trigger an avalanche
- High gain
- Correlated avalanche noise

Breakdown voltage

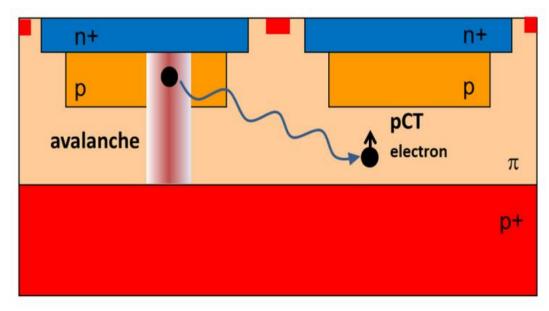




- Breakdown voltage increases linearly with temperature.
- Relative logarithmic derivation method to extract the breakdown voltage.
- Landau fit function on $\frac{d(\ln(I))}{dV}$ and mean value gives the breakdown voltage.

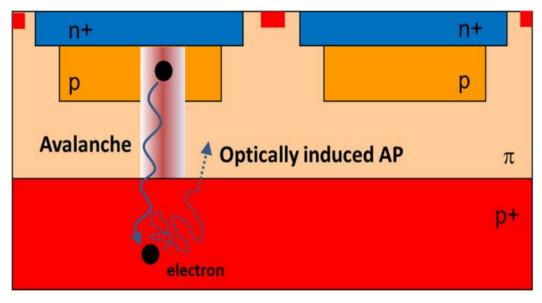
Correlated noise parameters

Cross-talk



- During avalanche, accelerated carriers in the high field region could emit photons
- That photon can initiate a secondary avalanche in a neighbouring microcell.

Afterpulsing



- Carriers get trapped in defects in the silicon.
- Released after a delay which initiate an avalanche in the same microcell.

Figures from Piemonte C and Gola A (2019)

Reverse bias fit model

Pre breakdown fit function:

$$I = q * C_{srh} * W_o * \left\{ \left(\left(1 - \frac{V}{V_{int}} \right)^p - 1 \right) + A \left(exp \left(\frac{V}{B} \right) - 1 \right) \right\}$$

 C_{srh} = Shockley-Read-Hall recombination factor

 W_o = Zero bias depletion layer width

 V_{int} , p = CV parameters

A, B = empirical parameters (Otte et al (2017))

Reverse bias fit model (contd.)

Post breakdown fit function: involves the contribution of dark noise and correlated noise – afterpulsing and cross-talk

$$I_{post} = C * R_{DN} * V_{ov} * \left(1 - exp\left(-\frac{V_{rel}}{\alpha}\right)\right) * \left\{\left(\frac{1}{1 - P_{AP}(V_{ov})}\right)\left(\frac{1}{1 - P_{CT}(V_{ov}^2)}\right)\right\} + I_{ov} + I_{ov}$$

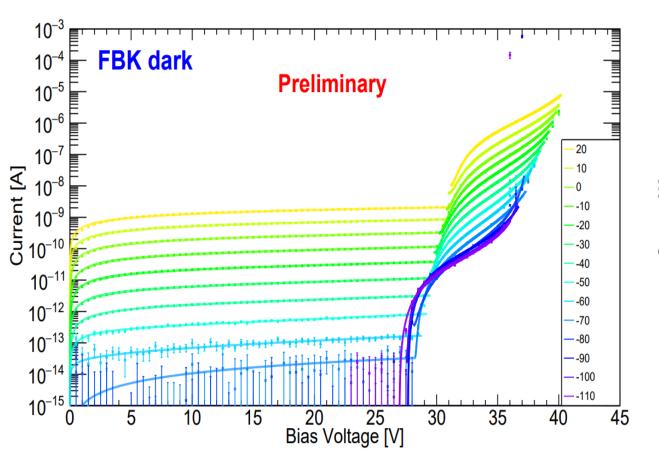
$$R_{DN} =$$
Dark noise rate $V_{ov} = (V - V_{br}) =$ Overvoltage , $V_{rel} = \frac{V_{ov}}{V_{br}}$

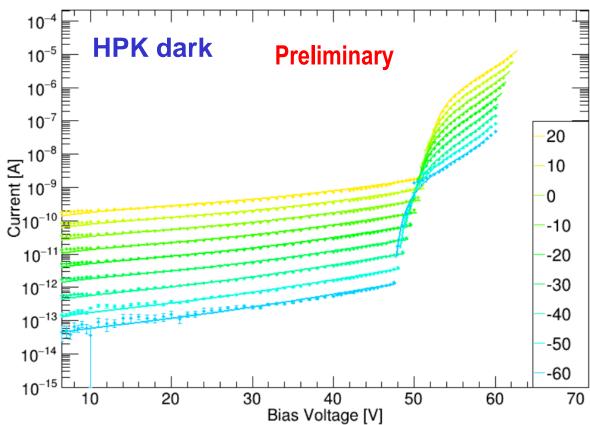
 $V_{br} = Breakdown voltage$; C = Capacitance; $I_o = leakage current$

 P_{AP} = probability of afterpulsing; P_{CT} = probability of crosstalk

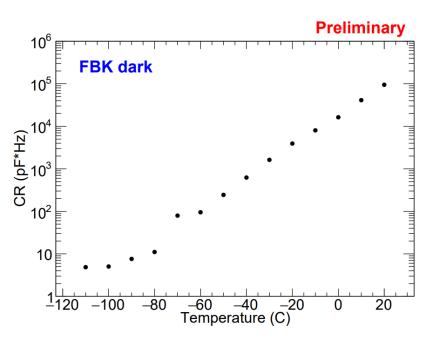
$$\left(1 - exp\left(-\frac{V_{rel}}{\alpha}\right)\right)$$
 = triggering probability

IV fits for 2 devices

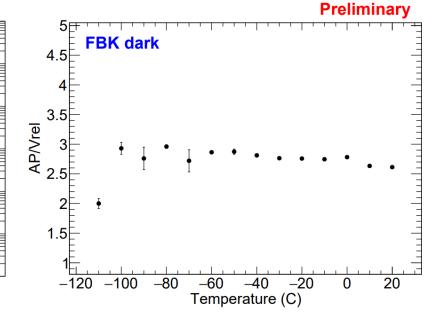




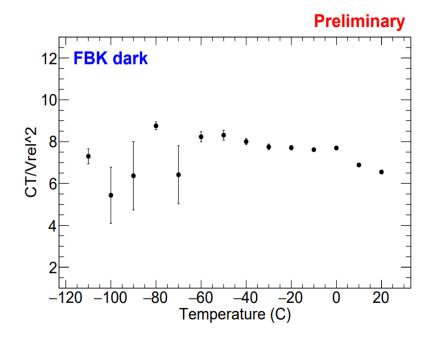
IV parameters



Considering C to be constant over different temperatures, R increases exponentially with temperature



Parameter AP(V) tends to stay constant with temperature, similar results are indicated in literature



Parameter CT(V²) tends to stay constant with temperature

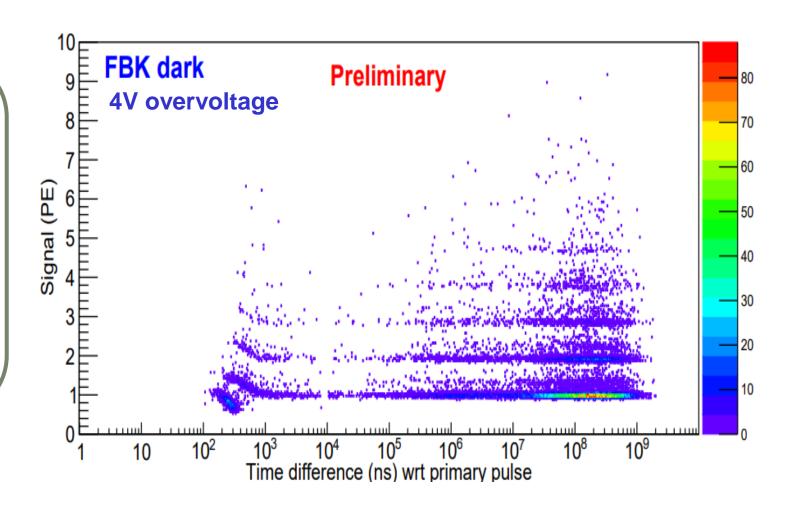
^{*} Only statistical error bars are shown

Pulse analysis

- SiPM pulse data was taken at two overvoltages (4 & 7V) at 0.5PE threshold.
- Primary pulse selection:

 It should be single PE (0.5 1.5PE)

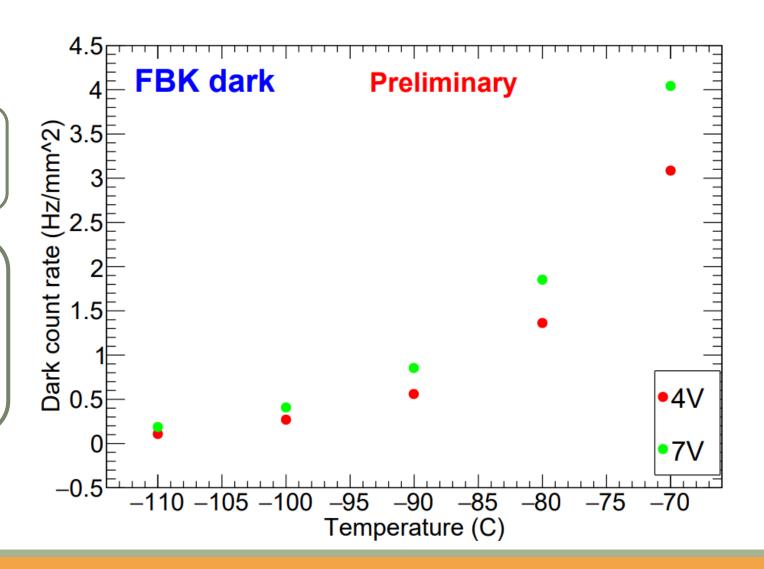
 It should happen atleast 500µs
 later than previous pulse.



Dark noise rate

$$Dark count \ rate = \frac{N_{>0.5PE}}{Run \ time \ (s)}$$

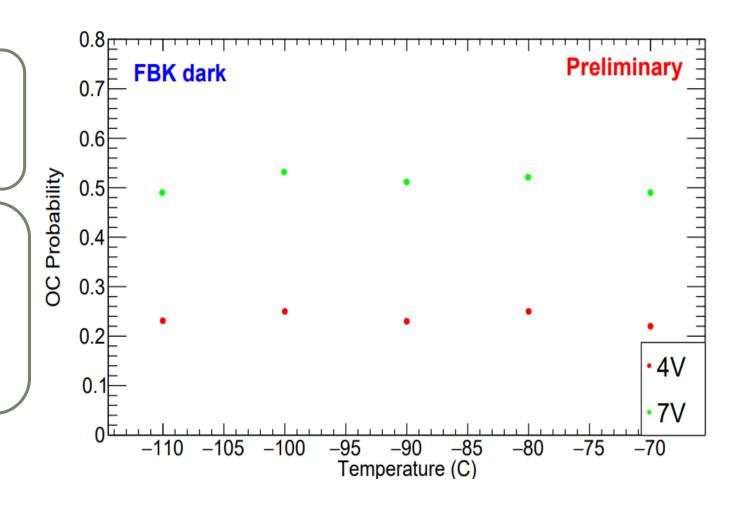
- Dark count rate (DCR) showed exponential rise with temperature
- It also increases with increase in overvoltage



Optical crosstalk

$$OC\ probability = \frac{N_{>1.5PE}}{N_{>0.5PE}}$$

- OC probability increases with overvoltage
- Crosstalk seems to be independent of temperature, similar results are indicated by IV analysis as well.



Summary and future plans

- IV characterization and fit model looks promising over a range of temperatures for both FBK and Hamamatsu SiPM devices
- Improve the IV model for dark data
- Extend the fit functions with some additional terms for light data
- •Improve pulse analysis for HPK device data
- Light data has already been taken and analysis for both IV and pulse data are ongoing
- •At TRIUMF, Cryo probe facility will use IV characterization to test thousands of SiPMs for nEXO.